

Model 215 NanoSpec[®]/AFT

Automated Film Thickness Measurement and Mapping System



Specifications

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Specifications for the Model 215 can be divided into wafer specifications, measurement specifications, system specifications, environmental specifications, and installation site specifications.

Wafer Specifications			
Wafer size	4" (100 mm), 5" (125 mm), 6" (150 mm)		
Wafer Indexing method	Flat or notch, configurable in Process Engineer mode		
Wafer cassettes			
Capacity	Two, with a maximum of 25 wafers each		
Туре	Any cassette that complies with SEMI standards for automatic wafer handlers, in the current <i>Book of SEMI</i> <i>Standards</i> , Volume 2, Equipment Automation Division, Chapter E1, published by the Semiconductor Equipment and Materials Institute, Incorporated		
Recommended cassettes	100 mm Fluoroware PA182-39MLB, 25 wafer capacity, blue polypropylene, Nanometrics p/n: 9720-0139		
	125 mm Fluoroware PA182-50MB, 25 wafer capacity, blue polypropylene, Nanometrics p/n: 9720-0140		
	150 mm Fluoroware PA182-60MB, 25 wafer capacity, blue polypropylene, Nanometrics p/n: 9720-0141		
Pick up	Vacuum wand touches only back side of wafer		
Selection	Completely random access, pick up and place, computer controlled		
Indexing	Non-contact centering: ± 0.5 mm Optical index orientation: $\pm 1^*$		
Measurement Specifications			

Thickness range	100Å to 500,000Å
Measurement spot sizes	5x objective: 50 microns 10x objective: 25 microns 50x objective: 5 microns

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Focus		
Programmed focus:	For use on patterned or unpatterned wafers with the 5x objective lens	
Auto focus	For use on patterned or unpatterned wafers with 5x, 10x, and 50x objective lenses	
Focus time	1.5 to 2 seconds	
Film types	oxide on silicon negative resist on silicon negative resist on oxide thin oxide on silicon polyimide on silicon positive resist on oxide thick films	nitride on silicon polysilicon on oxide nitride on oxide thin nitride on silicon positive resist on silicon positive dyed resist on silicon

System Specifications

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Stage

Movement	t range	X: 150 mm Y: 150 mm Theta: 360°		
Drive		X, Y and Z via computer controlled stepper motors		
X/Y slew n	ate	25 mm per second		
Resolution	n	0.08 microns (minimum stage movement increment)		
Position reproduci	bliity	±5 microns		
Standard program-Up to 499 sites per wafer mable positions				
Objective ler	nses			
Available	neel	These infinity corrected tube langth ner centered no		

Available posi- tions	Three, infinity corrected tube length, par-centered, par- focal	
Selection	Fully automatic, computer controlled	
Change time	1 second	

System control

	Metrology com- puter (MC1)	IBM PC/AT-compatible 80386-based processor with 80387 numeric coprocessor, 4 megabytes of system memory, one 40 megabyte hard disk drive, one 1.2 megabyte floppy diskette drive, EGA display adapter		
	NanoStation com- puter (NS1)	IBM PC/AT-compatible 80286-based processor with 80287 numeric coprocessor, 640 kilobytes of system memory, one 40 megabyte hard disk drive, one 1.2 megabyte floppy diskette drive, EGA display adapter		
	Computer Monitor	13" RGB color graphics monitor capable of displaying 640 dots (horizontal) by 480 dots (vertical) for VGA resolution		
	Communication	Full SECS-II compatibility		
Environmental Specifications				
	Operating temperature	45°F ω 80°F (7°C ω 27°C)		
	Humidity	20% to 80%, noncondensing		
Installation Site Specifications				
	Location	Any solid, level surface void of excessive vibration (whether mechanically or acoustically induced), and void of electromagnetic and magnetic fields		
	Power			
	Domestic	115 Vac nominal (+10%, -15%), single phase, 50/60 Hz Connector: 8A two pole/three-wire twist-lock #3334-GC		
	International	225 Vac nominal (±25V), 50/60 Hz Connector: supplied by user due to wide differences in approved types		
 Important The NanoStation regardless of syste power circuitry the operating from 2 computer display Connecting ther cause severe dan 		and computer display operate at 115 Vac nominal, iem power setting. The computer tower has internal hat provides 115 Vac to the switched outlets when 225 Vac. Always connect the NanoStation and by to the switched outlets on the back of the tower. Im to facility power of the wrong voltage may mage.		
	Vacuum	10" mercury $(\pm 1")$ Connector: Swagelok, QC4 series (accepts clean cut, 3/8" flexible tubing		
	Footprint (width x depth x height)	38" (97 cm) x 28" (71 cm) x 30" (76 cm)		
	Weight	Approximately 210 lb (95 kg)		